



COPY

THE UNITED STATES PATENT AND TRADEMARK OFFICE

In re application of: BAILEY III et al.

Attorney Docket No.: LAM1P124D1

Application No.: 09/943,806

Examiner: Alejandro Mulero, Luz L

Filed: August 30, 2001

Group: 1763

Title: TEMPERATURE CONTROL SYSTEM
FOR PLASMA PROCESSING APPARATUS

RECEIVED
APR 07 2003
TC 1700

CERTIFICATE OF MAILING

I hereby certify that this correspondence is being deposited with the United States Postal Service as First Class Mail to Box Non-Fee Amendment, Commissioner for Patents, Washington, DC 20231 on November 27, 2002.

Signed: Sue Funchess

Sue Funchess

AMENDMENT C

Box Non-Fee Amendment
Commissioner for Patents
Washington, DC 20231

Sir:

This Amendment is in response to the Office Action (identified as paper no. 10) mailed October 10, 2002. Applicants representative kindly thanks the Examiner for her helpful guidance during the telephonic interview of November 26, 2002. Applicant's representative respectfully requests entry of this amendment. Please amend the above-entitled application as set forth below.

In The Claims:

Please CANCEL, without prejudice, claims 24, 25, and 34 as follows.

Please AMEND the claims as follows:

(Twice amended) 23. A method for providing temperature control to a plasma processing chamber of a plasma processing apparatus, said method comprising:

directly or indirectly measuring temperature internal to the plasma processing chamber;